

2024 SPIE Advanced Lithography + Patterning Conference

February 25 – February 29, 2024, San Jose, CA.

Papers and events of interest that include Fractilia authors:

	Paper	Location	Title	Presenter/Authors
Tuesday				
1:50 pm	12953-17	Grand Ballroom 220A	Modeling edge placement error performance of EUV and DSA multipatterning processes	Chris A. Mack, Fractilia Co-authors: Intel
3:00 pm	12955-20	Grand Ballroom 220B	Practical LWR sampling approaches for advanced patterning	Pulkit Saksena, Intel Co-authors: Fractilia
Wednesday				
3:20 pm	12955-43	Grand Ballroom 220B	Evaluating the probabilistic process window for use in high volume manufacturing	Chris A. Mack, Fractilia Co-authors: Nanya
Thursday				
4:20 pm	12955-61	Grand Ballroom 220B	Simulating SEM imaging of via bottoms	Ben Bunday, AMAG Co-authors: Fractilia

Papers by other authors will also include Fractilia results.